

eWLB

Embedded Wafer Level Ball Grid Array

We offer customers a high performance fan-out wafer level packaging (FOWLP) solution that provides significant bandwidth, performance, form factor and cost benefits compared to other packaging technologies available today.

Proven Leadership

- Versatile platform for advanced system level integration
- Highest integration density commercially available in the industry today
- Flexibility to integrate die from diverse processes, manufacturing sources & silicon wafer nodes for increased functionality
- Excellent mechanical, electrical & thermal performance
- Effectively accommodates new lithography nodes
- Flexible, cost effective 2D, 2.5D & 3D solutions across a broad range of market segments & applications

Features

Performance

- Unprecedented flexibility in 2.5D & 3D integration with Si partitioning capabilities
- Advanced dielectric materials for highly reliable, power-efficient solutions
- Strong electrical performance (capable to beyond 80GHz) and throughput for mmWave/5G devices
- Highly effective heat dissipation for strong thermal performance
- KGD process helps achieve strong yields (99.9%)

Form Factor

- Maximum I/O density; 1.5-2X increase in routing density in the smallest, thinnest footprint commercially available today
- Thin film processing enables very fine lines for X,Y routing (line and width spacing down to 2µm/2µm), very fine via pitches & thin dielectrics
- Die-to-die, die-to-passives, & passives-to-passives placement distances below 100µm
- Fine pitch copper (Cu) pillar bumps provide tighter pitch for 2.5D/3D designs
- Industry's thinnest 3D PoP solutions (ultra thin z-height of 0.3mm with stacked thickness down to 0.8mm height)

Cost

- Well established, high volume manufacturing process enables scaling devices to larger panel sizes for cost reduction
- Thin film interconnection offers lowest cost structure over competing advanced manufacturing approaches
- Elimination of substrate results in a thinner package with lower warpage, simplifies supply chain & reduces costs
- 2.5D and 3D options offers a more cost effective & infrastructure-friendly alternative to expensive TSV integration

Market Leader in FOWLP Technology

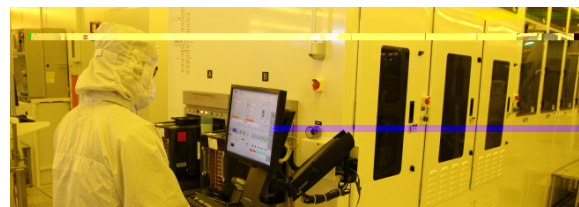
Embedded Wafer Level Ball Grid Array (eWLB) is a versatile fan-out wafer level packaging platform (FOWLP) designed to address the growing mismatch in interconnect gap, higher levels of integration, improved electrical performance and shorter vertical interconnects. The eWLB platform provides a more space-efficient package design enabling a smaller footprint, higher density input/output (IO) and lower package profiles.

Assembled directly on a silicon wafer, this chip-first, face-down FOWLP approach is unconstrained by die size, providing the design flexibility to accommodate an unlimited number of interconnects between the package and the application board for maximum connection density, finer line/spacing, improved electrical and thermal performance and small package dimensions to meet the relentless form factor requirements and performance demands of the mobile market.

eWLB's flexible manufacturing process can reduce substrate complexity and costs while achieving very dense interconnection in a range of reliable, low-warpage 2D, 2.5D and 3D solutions including small die, large die, stacked or side-by-side multi-die and ultra-thin options across a broad range of market segments and applications.

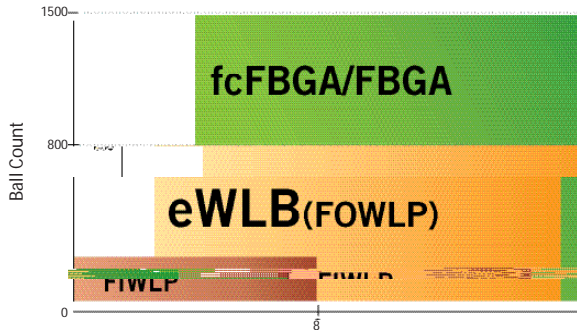
The basic structure of eWLB, thin film processing, has enabled us to create eWLB-based interposers that can connect one active die to another, enabling very dense interconnection with more effective heat dissipation, improved processing speed and the flexibility to integrate die from different manufacturing sources. The result is a proven 2.5D solution that is superior to Through Silicon Via (TSV) in terms of overall cost effectiveness and process simplicity.

Our 3D System-in-Package (SiP) and Package-on-Package (PoP) solutions include embedded multiple passives and active components, face-to-back or face-to-face options, and single-sided, 1.5-sided and double-sided ultra-thin PoP configurations. For applications requiring full 3D integration, our face-to-face eWLB PoP configuration provides a direct vertical interconnection between an application processor die and a memory die through the eWLB mold layer to enable a high bandwidth, very fine pitch structure with performance that parallels TSV technology.



Application Space

When determining the optimal platform among the space of device I/O densities and product architectures, early stage co-design helps ensure the lowest cost solution. As the gap between chip I/O and PCB density increases, we have analyzed the fan-out ratio of different package designs and identified the “sweet spot” for eWLB.



eWLB expands the application space for Wafer Level Packaging

Component Level Reliability

Moisture Sensitivity Level	MSL1 @ lead free condition (260°C)
Temperature Cycling (after precon)	-55°C/125°C, 1000 cycles
Unbiased HAST	130°C/85% RH, 96 hrs
High Temperature Storage	150°C, 1000 hrs
Temperature Humidity Bias Test	85°C/85%/5V, 1000 hrs
High Temperature Operating Life	JESD22-A109, 125°C, 1000 hrs
Multiple Solder Re-flow	5x, 10x and 20x re-flows with minimal reduction in bump shear strength

Board Level Reliability

Temperature Cycling on Board	-40°C/125°C, 2 cycles/hr, 500 cycles
Drop Test	Passed JEDEC drop test for 8 x 8mm, 183 balls (0.5mm pitch)
Bend Test	Passed JEDEC bend test, 300 cycles
Temperature Humidity Bias Test	85°C/85%, RH, 5V, 1000 hrs (performed mounted on PCB)

Thermal Performance θ_{ja} (°C/W)

Thermal performance is highly dependent on package size, die size, substrate layers and thickness, and solder ball configuration. Simulation for specific applications should be performed to obtain maximum accuracy.

Body Size	Die Size	Thermal Performance θ_{ja} (°C/W)	Thermal Vias (on test board)
8 x 8mm	5 x 5mm	32.5	simulation data
12 x 12mm	8 x 8mm	21.7	simulation data
14 x 14mm	10 x 10mm	17.7	simulation data

Notes: Thermal performance in the 15-35°C/W range without thermal enhancement. Application specific thermal characterization available upon request.

eWLB Process Flow

1. Reconstituted wafer
 - Wafer saw and pick-and-place from incoming wafer
 - Probed good die
 - Molded reconstituted wafer using proven materials
 - Molded artificial wafer starting point for thin film technology
2. Redistribution
 - Thin film technology with advanced design rules
 - Standard thin film equipment
 - Proven and reliable material set
3. Ball Mount and Singulation
 - Standard back-end assembly flow (and equipment)

Specifications

Body sizes	2 x 2mm to 12 x 12mm in high volume production; up to 16 x 16mm qualified
Bump Pitch	0.3mm minimum
Bump Height	0.16mm/0.2mm / 0.23mm (0.35mm / 0.4mm / 0.5mm pitch)
Backside Coating	Laminated coating (optional)
Marking	Laser marking
Inspection	Automatic optical inspection w/ electronic wafer mapping
Packing Options	Fully automated die pick/place into custom pocket tape/reel or wafer pack media

eWLB-PoP	3D Face-to-Face
3D eWLB with interposer	
2.5D/Extended eWLB	
Flip Chip eWLB	